DOCKET NO. 07CV822 (AKH)

ANVIK CORPORATION

PATENT OR

TRADEMARK NO.

1 See Attached Sheet

PLAINTIFF

TO: Mail Stop 8

Director of the U.S. Patent and Trademark Office P.O. Box 1450 Alexandria, VA 22313-1450

> DATE FILED 2/2/2007

> > DATE OF PATENT

OR TRADEMARK

REPORT ON THE FILING OR DETERMINATION OF AN ACTION REGARDING A PATENT OR TRADEMARK

Southern District of New York

HOLDER OF PATENT OR TRADEMARK

AU OPTRONICS CORPORATION, ET AL.,

In Compliance with 35 U.S.C. § 290 and/or 15 U.S.C. § 1116 you are hereby advised that a court action has been filed in the U.S. District Court Southern District of New York on the following Trademarks or of Patents. (the patent action involves 35 U.S.C. § 292.):

U.S. DISTRICT COURT

See Attached Sheet

45,291,290							
5							
1	In the above—entitled case, the fo	llowing patent(s)/ trademar	k(s) have been includ	ed:			
DATE INCLUDED	INCLUDED BY	iment	☐ Cross Bill	Other Pleading			
PATENT OR TRADEMARK NO.	DATE OF PATENT OR TRADEMARK	HOLDI	ER OF PATENT OR	TRADEMARK			
I See Attached Sheet	See Attached Sheet						
2							
3							
4							
5							
In the above—entitled case, the following decision has been rendered or judgement issued:							
DECISION/JUDGEMENT							
COPY ATTACHED: JUDGMENT							
_							
		1.4	/	In order			
CLERK	(BY)	DEPUTY CLERK	•	DATE 4/6/2012			
Ruby J. Krajick							
Copy 1—Upon initiation of action, mail this copy to Director Copy 3—Upon filing document adding patent(s), mail this copy to Director Copy 4—Case file copy							

UNITED STATES DISTRICT COURT SOUTHERN DISTRICT OF NEW YORK

USDC SDNY
DOCUMENT
ELECTRONICALLY FILED
DOC #:
DATE FILED: 4/12

ANVIK CORPORATION,

Plaintiff,

NIKON PRECISION, INC., et al.,

LG.PHILIPS LCD CO., LTD., et al.,

SAMSUNG ELECTRONICS AMERICA, INC., et al.,

CHI MEI OPTOELECTRONICS, et al.,

AU OPTRONICS CORP., et al.,

SHARP CORP., et al.,

INNOLUX DISPLAY CORP.,

HANNSTAR DISPLAY CORP.,

AFPD PTE LTD., and IPS ALPHA TECHNOLOGY, LTD, et al.

Defendants.

Civ. No. 05-7891 (AKH)

Civ. No. 07-0816 (AKH)

Civ. No. 07-0818 (AKH)

Civ. No. 07-0821 (AKH)

Civ. No. 07-0822 (AKH)

Civ. No. 07-0825 (AKH)

Civ. No. 07-0826 (AKH)
Civ. No. 07-0827 (AKH)

Civ. No. 07-0828 (AKH)

Civ. No. 08-4036 (AKH)

JUDGMENT

Upon the Court's Order of April 42012 (the "Order"), it is hereby ordered that the above-captioned actions are dismissed upon the following terms:

 Claims 17 and 18 of U.S. Patent No. 4,924,257 are declared invalid for failure to comply with the requirement that "[t]he specification . . . shall set forth the best mode contemplated by the inventor of carrying out his invention." 35 U.S.C. § 112.

- Claims 23 and 25 of U.S. Patent 5,285,236 are declared invalid for failure to
 comply with the requirement that "(t)he specification . . . shall set forth the best mode
 contemplated by the inventor of carrying out his invention." 35 U.S.C. § 112.
- Claim 25 of U.S. Patent 5,291,240 is declared invalid for failure to comply with
 the requirement that "(t)he specification . . . shall set forth the best mode contemplated by the
 inventor of carrying out his invention." 35 U.S.C. § 112.
- Plaintiff's Complaint or Amended Complaint, as the case may be, in each of the above-captioned actions is dismissed with prejudice.
 - This is without prejudice to Plaintiff's right to appeal.
- Defendants' Counterclaims, other than those asserting invalidity of U.S. Patents
 Nos. 4,924,257, 5,285,236, and 5,291,240 in each of the above-captioned actions, are dismissed without prejudice as moot.

April 5_, 2012

CLERK OF COURT

United States Patent [19]

Patent Number: 1111 Date of Patent:

4,924,257 May 8, 1990

	PROJECTION LITHOGRAPHY SYSTEM			
[76]	Inventor:	Kantilal Jain, 18 Algonquian Trail, Briarcliff Manor, N.Y. 10510		
[21]	Appl. No.:	253,717		
[22]	Filed:	Oct. 5, 1988		
[51]	Int. CL ³	G03B 27/42		
[52]	U.S. Cl	355/53; 355/77;		
(,		250/492.2		

[54] SCAN AND REPEAT HIGH RESOLUTION

[58] Field of Search .. 355/43, 53, 77; 356/400, 401; 250/548, 442.1, 205, 491.1, 492.2,

References Cited 1561 IIS PATENT DOCUMENTS

	4,748,477	5/1988	Morita et al	

Primary Examiner-L. T. Hix Assistant Examiner-D. Rutledge Attorney, Agent, or Firm-Carl Kling

Jain

ABSTRACT This scan and repeat lithography system has high resolution capability, large effective image field size, and high substrate exposure speed, and comprises: (a) a substrate stage capable of scanning a substrate in one dimension and, when not scanning in said dimension, capable of moving laterally in a direction perpendicular to the scan direction so as to position the substrate for another scan; the substrate stage exposing the full substrate by breaking up the substrate area into parallel strips, and exposing each of the strips by scanning the length of the strip across a fixed illumination region; (b) a mask stage capable of scanning in the same direction as, and synchronized with, the substrate stage, at a speed faster than the substrate stage scanning speed by a certain ratio M; (c) an illumination subsystem having an effective source plane in the shape of a polygon, and capable of uniformly illuminating a polygon-shaped region on the mask; (d) a projection subsystem having an object-to-image reduction ratio M, and having a polygon-shaped image field of an area smaller than the desired effective image field size of the lithography system; and (e) provision of complementary exposures in an overlap region between the areas exposed by adjacent scans in such a way that a seam in the exposure dose distribution received on the substrate is absent between the scans, and such that the exposure dose delivered across the entire substance is uniform.

22 Claims, 5 Drawing Sheets

